



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Re U.S. Patent application: )

Hisato SHINOHARA et al. )

Application Serial No. 08/169,127 )

Art Unit: 1762

Filed: December 20, 1993 )

Examiner: Marianne L. Padgett

For: METHOD AND SYSTEM OF  
LASER PROCESSING )

**SUPPLEMENTAL AMENDMENT**

Mail Stop AMENDMENT  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

In response to the Office Action mailed May 19, 2004, and to the Examiner interview conducted April 19, 2005, please consider the following amendments and remarks in connection with this instant application.